

ABSTRACT

Method, Apparatus and Computer Product for Substrate Processing

5 A method, apparatus and computer product for processing of substrates in at least a part
of a substrate processing system is provided. In an embodiment, the method includes obtaining,
using a processing unit, at least one of a rate of processing and a time of processing of a plurality
of substrate lots to be introduced into a part of the substrate processing system and determining,
using the processing unit, an order of introduction of the plurality of substrate lots into the part
10 of the substrate processing system to at least one of increase the rate of processing and decrease
the time of processing of the plurality of substrate lots.